

UR Integrated Nanosystems Center User Facility Individual Authorization Form

User's Name _____ Phone Ext or Cell _____

Last _____ First _____

UR ID _____

Email Address _____

Advisor/Principal Investigator Last Name _____

Status (circle one) Graduate Student Undergrad Class of _____ REU Postdoc

Tool Access to be Granted (circle all that apply) Metrology-Wilmot Clean Room - Goergen

I agree to the terms and conditions below:

All time I schedule will be billed to the research group I am currently a member of. If I am not going to use a tool, I will cancel my reservation at least 24 hours before the reservation begins, otherwise the costs will be billed to the professor. Billing will be based on either scheduled time or actual elapsed time (when available). I will not do work that is of a personal nature without setting up a personal account. I will only use my ID card to swipe into the facilities. I will not use my ID card to swipe other individuals into the facility. All issues, corrections or concerns with the scheduling tool PPMS will be email documented to the administrator urnano@pas.rochester.edu. Any requests for a change in charge because of tool malfunction will need to have been documented by an incident report in PPMS during the session along with email documentation to the administrator urnano@pas.rochester.edu

Signature _____ Date _____

Billing Authorization Information

Account Number _____ Percentage _____ % Acct Exp Date: _____

Account Number _____ Percentage _____ % Acct Exp Date: _____

(Please denote if 100% to one account or percentage to be split between multiple accounts)

PI Signature or Administrator _____ Date _____

Charges will be processed monthly for hourly users of equipment and facilities. Invoiced amounts will automatically be charged against the account listed above. Rejected account numbers will result in access denial to Labs, to all individuals within the PI's group.

Scheduler can be found at: <http://ppms.us/urmc>

URNano site : <https://www.rochester.edu/urnano/>

Metrology	Sample Prep	Cleanroom		
SEM	Sputter	RIE	Lithography	Safety
TEM	Plasma Clean	ALD	AJA	Wet Processing
FIB	Evaporator	CVD	Wire Bonder	Cleaning
STEM	Tripod	PVD-75	Other: _____	
AFM	Plasma trim	RTP		
X-ray				